



U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

MAILED

REQUEST FOR EXTENSION
OF TIME PURSUANT TO
37 C.F.R. § 1.136(a)

Docket Number: 10191/1466 APR 15 2002

GROUP 1700

Application Number
09/581,663

Filing Date
August 3, 2000

Examiner
S. AHMED

Art Unit
1746

Invention Title

METHOD FOR PROCESSING SILICON
BY ETCHING PROCESSES

Inventor:
Volker BECKER et al.

COPY OF PAPERS
ORIGINALLY FILED

Assistant Commissioner
for Patents
Washington, D.C. 20231

I hereby certify that this correspondence is being deposited
with the United States Postal Service as first class mail in an
envelope addressed to: Assistant Commissioner for Patents,
Washington, D.C. 20231 on
Date: March 27, 2002

Reg. No. 36,197

Signature: 

Jong H. Lee

Applicants respectfully request a one-month extension of time in
which to respond to the office action dated December 21, 2001, for which
a response period expiring on March 21, 2002 was set. The extended
period expires on April 21, 2002.

1. The Commissioner is hereby authorized to charge payment of the
37 C.F.R. § 1.136 extension fee of **\$110.00** to the Deposit Account of
Kenyon & Kenyon, Deposit Account number **11-0600**. The office is also
authorized to charge any additional fees, or credit overpayments, associated
with this paper to Deposit Account **11-0600**.

2. A duplicate copy of this form is enclosed.

Dated: March 27, 2002

By: 

Jong H. Lee (Reg. No. 36,197)

KENYON & KENYON

CUSTOMER NO. 26646
PATENT TRADEMARK OFFICE

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